

| | | | | | |
|-----------------------------------|--|--|-------------------------|--|-------------|
| Notice of References Cited | | | Application/Control No. | Applicant(s)/Patent Under Reexamination KURIMURA ET AL. | |
| | | | Examiner John D. Lee | John D. Lee Art Unit 2874 | Page 1 of 1 |

U.S. PATENT DOCUMENTS

| * | | Document Number Country Code-Number-Kind Code | Date MM-YYYY | Name | Classification |
|---|---|--|-----------------|---------------|----------------|
| * | A | US-5,781,670 | 07-1998 | Deacon et al. | 385/10 |
| | B | US- | | | |
| | C | US- | | | |
| | D | US- | | | |
| | E | US- | | | |
| | F | US- | | | |
| | G | US- | | | |
| | H | US- | | | |
| | I | US- | | | |
| | J | US- | | | |
| | K | US- | | | |
| | L | US- | | | |
| | M | US- | | | |

FOREIGN PATENT DOCUMENTS

| * | | Document Number Country Code-Number-Kind Code | Date MM-YYYY | Country | Name | Classification |
|---|---|--|-----------------|---------|------|----------------|
| | N | | | | | |
| | O | | | | | |
| | P | | | | | |
| | Q | | | | | |
| | R | | | | | |
| | S | | | | | |
| | T | | | | | |

NON-PATENT DOCUMENTS

| | | |
|---|---|---|
| * | | Include as applicable: Author, Title Date, Publisher, Edition or Volume, Pertinent Pages) |
| | U | Kurimura et al, "Shigai Hacho Henkan o Mezashita Giji Iso Seigo Suishi" ("Quasi-Phase-Matching Quartz Aiming at Ultraviolet Wavelength Conversion"), OYO BUTSURI, vol. 69, no. 5, pp. 548-552, June 2000. |
| | V | |
| | W | |
| | X | |

*A copy of this reference is not being furnished with this Office action. (See MPEP § 707.05(a).)
Dates in MM-YYYY format are publication dates. Classifications may be US or foreign.